## Understanding the Growth of Thin Oxide Films

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National Defense Science and Engineering Graduate Fellowship (NDSEG)







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# Background

Bachelor's Chemical Engineering from University of Dayton 2018

- National Renewable Energy Laboratory (polymers)
- University of Dayton Research Institute (composites)
- Air Force Research Laboratory (transition metal dichalcogenides)

PhD Case Western Reserve University, 4<sup>th</sup> year Materials Science and Engineering (thin film oxides)

- Member of ACerS and ASM
- Expected graduation: August 2022

National Defense Science and Engineering Graduate Fellow



University of Dayton







# Motivation

Understanding the growth of multilayer heterostructure oxides

- These structures can be built into devices
- Specifically, I aim to achieve single crystal films to understand ionic and electronic conductivity of LiCoO<sub>2</sub>
- Utilize data science to better understand growth characteristics of oxides in pulsed laser deposition



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# Overview

- Brief background of techniques
- Thin film growth and structural characterization
  - SrRuO<sub>3</sub> (SRO)
  - LiCoO<sub>2</sub> (LCO)
- Applied data science work

Applied Physics	METHOD	scitation.org/journal/jap		
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			- Ela	
Cite as: J. Appl. Phys. <b>130</b> , 125301 (2021); doi: 10.1063/5.0059655 Submitted: 10 June 2021 · Accepted: 29 August 2021 · Published Online: 22 September 2021		View Online	Export Citation	CrossMark
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## **Pulsed Laser Deposition**

- Pulsed laser deposition (PLD) can make heterostructures of thin films
- PLD uses a laser to deposit a film from a target of the material of interest in a controlled environment
- Parameters: temperature of substrate, background oxygen pressure, laser energy, laser spot size, laser frequency, target composition
- There are three growth modes a. island b. layer-by-layer c. step flow



Corrosion, C. Pulsed Laser Deposition PLD Explained With Animations. (2019).





Background

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## **Reflection High Energy Electron** Diffraction



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# Data Science

- Unsupervised learning techniques use unlabeled data
- Dimension Reduction reduces the overall amount of data, particularly from variables, without losing integrity
  - Principal component analysis (PCA)
  - Nonnegative matrix factorization (NMF)
  - Kmeans Clustering

Time (s)	X1Y1	X2Y1	 X1Y2
0.25	1.0	1.0	 1.0
0.50	1.0	1.0	 1.0
0.75	1.0	1.0	 1.0

Background

James, G., Witten, D., Hastie, T. & Tibshirani, R. *An Introduction to Statistical Learning: with applications in R*. (Springer, 2013). doi:10.1007/978-1-4614-7138-7



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## Processing

# Thin Film Processing



- SrTiO<sub>3</sub> (100) substrates
- Etch substrates for TiO<sub>2</sub> termination
- KrF Excimer laser (248 nm)
- Stoichiometric SrRuO<sub>3</sub> target
- Stoichiometric LiCoO<sub>2</sub> target



Processing

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# SrRuO<sub>3</sub>: Comparison



- Both SRO had temperature = 670° C, pulse frequency = 2 Hz, fluence = 1.5 J/cm<sup>2</sup>
- The SRO grown at 13.3 Pa has intensity oscillations that fade away
  - This is caused by either step flow growth or island growth

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• The SRO grown at 6.7 Pa has intensity oscillations that continue

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# SrRuO<sub>3</sub>: Comparison



# LiCoO<sub>2</sub>

Time of flight secondary ion mass spectroscopy

- Used to identify presence of elements within a sample
- LCO was grown at conditions in the range of literature values
  - Oxygen can scatter lithium in PLD
  - Lithium is more volatile and is more susceptible to loss at higher temperatures •

LCO deposited at 670° C and 13.3 Pa



# LiCoO<sub>2</sub>: RHEED



Temperature = 620°C, Pressure = 26.7 Pa, 1500 pulses

From this diagram, I chose two sets of conditions to examine further.

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## Atomic Force Microscopy





Substrate = STO Temperature =  $620^{\circ}$  C Pressure = 26.6 Pa Fluence = 0.75 J/cm<sup>2</sup> Frequency = 10 Hz Pulses = 1500

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## Atomic Force Microscopy

#### Thin sample (300 pulses)





#### Thick sample (1000 pulses)



Substrate = SRO/STO Temperature = 620° C Pressure = 26.6 Pa Fluence = 0.53 J/cm<sup>2</sup> Frequency = 5 Hz



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## X – Ray Diffraction



- The right XRD pattern has more impurity phases in the lower angles
- This same pattern has shoulders for the (001) and (002) peaks
- The left XRD pattern has another peak right next to the (002) STO peak. This extra peak signifies LCO

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## X – Ray Reflectivity



Substrate = STO, Temperature =  $620^{\circ}$  C, Pressure = 26.6 Pa, Fluence = 0.75 J/cm<sup>2</sup>, Frequency = 10 Hz Pulses = 1500

Substrate = SRO/STO, Temperature =  $620^{\circ}$  C, Pressure = 26.6 Pa, Fluence = 0.53 J/cm<sup>2</sup>, Frequency = 5 Hz, Pulses = 1000

Processing

- The interface looks sharper on the right image
  - This may only be accounting for the sharp interface of SRO/STO
- The thickness of LCO on the left sample is much greater than that of the right sample
  - This could be just picking up SRO in B, whereas thickness only accounts for LCO in A.

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## Data Science

# LaAlO<sub>3</sub>



- Grows layer-by-layer over a range of conditions
- This sample was grown:
  - Temperature =  $770^{\circ}C$
  - Fluence =  $1.5 \text{ J/cm}^2$
  - Pulse frequency = 2 Hz
  - Background oxygen
    pressure = 0.1 mTorr
  - All samples grown on  $TiO_2$  terminated SrTiO<sub>3</sub>

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## Principal Component Analysis



- PC1: positive scores dominate in the beginning and correspond to the (00) spot in loadings. Negative scores dominate later and correspond to (01), (0-1). Minimum in scores corresponds to maximum of (0-1)
- PC2: relates to (00) spot; scores decrease with increasing thickness. (00) contains information from the substrate.
- PC4 Effects from incoherent scattering, correction to intensity from PC1
- Intensity oscillation phase shift

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## Same phase shift in other materials



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## Nonnegative Matrix Factorization



## Nonnegative Matrix Factorization



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#### Incoherent scattering is present in both cluster 2 in NMF and PC 4

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## Nonnegative Matrix Factorization



- NMF automatically separated the (00) and (0-1) diffraction spot information
- In PC1 the information from the different diffraction spots is mixed



# Kmeans



- Clusters 1 and 3 emphasize the (00) spot
- The (01) and (0-1) spots are more prominent in cluster 2
- Cluster 2 is increasing with time, whereas 1 and 3 decrease, indicating (00) relates to substrate

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Changing the spot the intensity is from changes the cluster at maximum

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# Conclusions

- Processing
  - The best growth conditions I have found so far are: temperature = 620° C, pressure = 26.6 Pa, fluence = 0.75 J/cm<sup>2</sup>, frequency = 10 Hz
  - This sample demonstrated a larger amount of LCO, and regions where the films were evenly spread across the surface
- Data Science
  - A shift in the intensity oscillations of different diffraction spots was noticed
  - Noise, as well as enhanced incoherent scattering were distinguished
  - NMF is the most easily interpreted method of the three unsupervised learning techniques

## What's Next?

- More structural characterization for understanding of epitaxial LCO/SRO/STO
- Electrical and electrochemical characterization
  - LCO/SRO/STO half cell
  - LLTO solid electrolyte

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**Questions?** 

